

Notice of References Cited	Application/Control No. 10/529,117	Applicant(s)/Patent Under Reexamination YOUNG ET AL.	
	Examiner M. Wilczewski	Art Unit 2822	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,881,615	04-2005	Yamazaki et al.	438/166
*	B	US-5,534,445	07-1996	Tran et al.	438/162
*	C	US-5,328,861	07-1994	Miyakawa, Tatsuya	438/151
*	D	US-4,692,344	09-1987	Kaganowicz et al.	438/762
*	E	US-5,529,951	06-1996	Noguchi et al.	438/487
*	F	US-5,470,763	11-1995	Hamada, Koji	438/162
*	G	US-5,288,645	02-1994	Toshima et al.	436/144
*	H	US-6,709,906	03-2004	Yamaguchi et al.	438/162
*	I	US-5,250,444	10-1993	Khan et al.	438/162
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Wolf et al., Silicon Processing for the VLSI Era, Volume 1-Process Technology, Sunset Beach, CA: Lattice Press, 1986, pp. 191-194.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.